

XA-9335

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Yutaka SUENAGA et al.

Appln. No.: 09/615,081

Group Art Unit:

Filed: July 12, 2000

Examiner: M. Robinson

For: CATADIOPTRIC OPTICAL SYSTEM AND EXPOSURE APPARATUS

EQUIPPED WITH THE SAME

AMENDMENT ACCOMPANYING REQUEST FOR CONTINUED EXAMINATION

Commissioner for Patents Washington, D.C. 20231

Sir:

Prior to continued examination, please amend the aboveidentified patent application as indicated below

03/14/2003 PBRITTON 00000001 09615081

IN THE CLAIMSON OP 01 FC:1202 02 FC:1201

- 28. (Twice amended) A projection exposure apparatus, 1
- comprising a catadioptric optical system according to Claim
- 18 which projects a predetermined pattern on a mask onto a
- photosensitive substrate.
- 40. (Amended) A projection exposure apparatus which
- projects a predetermined pattern on a mask onto a

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